

Amendments to the Claims

This listing of claims will replace all prior versions, and listings, of claims in the application:

1-25. (Canceled)

26. (Currently amended) A method of fabricating ordered patterns of nanoscale objects on a substrate surface comprising:

applying a resist layer to a substrate surface;

stamping an imprint mold having nanoscale teeth onto the resist layer; and

releasing the imprint mold to expose a template having a template surface formed into the imprint resist layer and having nanoscale openings formed therein to receive nanoscale objects;
and

depositing a plurality of discrete nanoscale objects onto the template such that the nanoscale objects are received within said nanoscale openings, said nanoscale objects are selected from a group consisting of nanoparticles, nanowires, nanorods, nanotubes, proteins, and DNA.

27. (Currently amended) A method according to Claim 26, further comprising selectively removing residual layer material from the substrate surface to expose portions of the substrate surface, and wherein at least some nanoscale objects are in contact with the exposed substrate surface ~~a template having a template surface formed into the imprint resist layer and having nanoscale openings formed therein to receive nanoscale objects.~~

28-30. (Canceled)

31. (Currently amended) A method according to Claim ~~26~~ 30, further comprising:
removing the nanoscale objects that remain outside of the openings with a chemical wash.
32. (Original) A method according to Claim 26, wherein the nanoscale openings are ordered
in a pattern with respect to at least one of the group consisting of size, shape, orientation, pattern,
and position.
- 33 -37. (Canceled)
38. (Currently amended) A method according to Claim ~~26~~ 28, further comprising attaching
DNA oligomers to the nanoscale objects, and wherein the first set of nanoscale objects are
proteins each configured to accommodate molecular attachment.
39. (Canceled)
40. (Canceled)
41. (Original) A method according to Claim 26, wherein the stamping is performed by a step
and flash lithographic method.
- 42-72. (Canceled)
73. (New) A method according to Claim 26, further comprising forming a first set of wires
below the template, and forming a second set of wires above the template, and wherein the
nanoscale objects are conductive and provide electrical connection between the first and second
sets of wires.